

Appl. No. : 10/082,397  
Filed : August 6, 2002

AMENDMENTS TO THE CLAIMS

The following listing of claims will replace all prior versions and listings of claims in the application:

Claims 1-67 (Canceled)

68. (Previously presented) An interferometric modulator comprising a sandwich of two or more layers, at least one of the layers comprising two or more films, the stress of each film being arranged so that the overall stress of the layer ranges from zero to tensile in magnitude; wherein the layers of the sandwich are movable relative to each other.

Claims 69-71 (Canceled)

72. (New) The interferometric modulator of Claim 68 wherein at least one of the layers comprises a support membrane.

73. (New) The interferometric modulator of Claim 72 wherein the support membrane has a tensile residual stress.

74. (New) The interferometric modulator of Claim 68 wherein the overall stress of at least one of the layers is zero.

75. (New) The interferometric modulator of Claim 68 wherein the overall stress of at least one of the layers is tensile.

76. (New) The interferometric modulator of Claim 68 wherein at least one of the layers comprises a mirror.

77. (New) The interferometric modulator of Claim 68 wherein at least one of the films comprises a metal.

78. (New) The interferometric modulator of Claim 77 wherein the metal comprises aluminum or silver.

79. (New) The interferometric modulator of Claim 68 wherein at least one of the films comprises an insulator.

80. (New) The interferometric modulator of Claim 79 wherein the insulator comprises silicon oxide or silicon nitride.

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81. (New) A method for making an interferometric modulator, comprising:  
forming a sandwich of two or more layers, at least one of the layers comprising  
two or more films;

arranging the stress of each film so that the overall stress of the layer ranges from  
zero to tensile in magnitude; and

configuring the layers of the sandwich to be movable relative to each other.

82. (New) The method of Claim 81 wherein at least one of the layers comprises a  
support membrane.

83. (New) The method of Claim 82 comprising arranging the stress of the support  
membrane to be a tensile residual stress.

84. (New) The method of Claim 81 comprising arranging the stress of each film so  
that the overall stress of at least one of the layers is zero.

85. (New) The method of Claim 81 comprising arranging the stress of each film so  
that the overall stress of at least one of the layers is tensile.

86. (New) The method of Claim 81 wherein at least one of the layers comprises a  
mirror.

87. (New) The method of Claim 81 wherein at least one of the films comprises a  
metal.

88. (New) The method of Claim 87 wherein the metal comprises aluminum or silver.

89. (New) The method of Claim 81 wherein at least one of the films comprises an  
insulator.

90. (New) The method of Claim 89 wherein the insulator comprises silicon oxide or  
silicon nitride.